

Title (en)

METHOD AND DEVICE FOR FORMING A MATERIAL PATTERN

Title (de)

VERFAHREN UND VORRICHTUNG ZUR HERSTELLUNG EINES MATERIALMUSTERS

Title (fr)

MÉTHODE ET DISPOSITIF POUR FORMER UN MOTIF DE MATIÈRE

Publication

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Application

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Abstract (en)

[origin: WO2019185626A1] The invention concerns a method and a device (3) for depositing a material pattern (61c) from a support (10) onto a substrate part (60). The deposition (202) of the material forming the pattern (61c) is preceded by a prior ejection that ejects material that is adjacent, on the support (10), to the material intended to form the pattern (61c).

IPC 8 full level

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See references of WO 2019185626A1

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